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[Abstract] [PDF Full-Text (368 KB)] IEEE CNF

2 Adaption of a microwave plasma source for low temperature diamond deposition

Ulczynski, M.; Reinhard, D.K.; Asmussen, J.; Plasma Science, 1996. IEEE Conference Record - Abstracts., 1996 IEEE International Conference on , 3-5 June 1996 Page(s): 138

[Abstract] [PDF Full-Text (108 KB)] IEEE CNF

3 Deposition of high photo-conductivity a-Si:H film using ICPs without substrate heating

Goto, M.; Toyoda, H.; Kitagawa, M.; Hirao, T.; Sugai, H.; Plasma Science, 1996. IEEE Conference Record - Abstracts., 1996 IEEE International Conference on , 3-5 June 1996 Page(s): 96 -97

[Abstract] [PDF Full-Text (156 KB)] IEEE CNF

4 Applications f intense pulsed light ion beams t materials